

INFORMATION DISCLOSURE CITATION*(Use several sheets if necessary)***Docket number (Optional)****15689.49.8****Application Number****10/673,863****Applicant(s)****Takehiro Nakamura et al.****Filing Date****September 29, 2003****Group Art Unit****2611****U.S. PATENT DOCUMENTS**

*EXAMINER INITIAL	REF	DOCUMENT NUMBER	DATE	NAME	CLASS	SUBCLASS	FILING DATE IF APPROPRIATE

U.S. PATENT APPLICATION PUBLICATIONS

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FOREIGN PATENT DOCUMENTS

	REF	DOCUMENT NUMBER	DATE	COUNTRY	CLASS	SUBCLASS	Translation	
							YES	NO
	1	0 682 418 A2	05/12/1995	EPO	H0487	005	X	
	2	CN1126930	7/17/1996	China	H04B7	005	X	

EXAMINER**DATE CONSIDERED**

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*Examiner
Initial

OTHER DOCUMENTS (Including Author, Title, Date, Pertinent Pages, Etc.)

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Chinese Office Action for Chinese Patent Application No.: 20031010330.1

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